



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of	)	Group Art Unit: 1773
Christopher C. CHANG et al.	)	Examiner: Nikolas J. Uhler
Application No.: 09/749,917	)	Confirmation No.: 6832
Filed: December 20, 2000	)	
For: LOW CONTAMINATION PLASMA	)	
CHAMBER COMPONENTS AND	)	
METHODS FOR MAKING THE	)	
SAME	)	

AMENDMENT AFTER FINAL REJECTION

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed February 20, 2004, please amend the  
above-identified patent application as follows:

*OK to enter*  
*WJ*  
*5/27/04*